# Design and Fabrication of Solid-State Photomultiplier(SSPM) composed of multi-pixel InGaAs SPAD

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WOORIRO Co., Ltd.



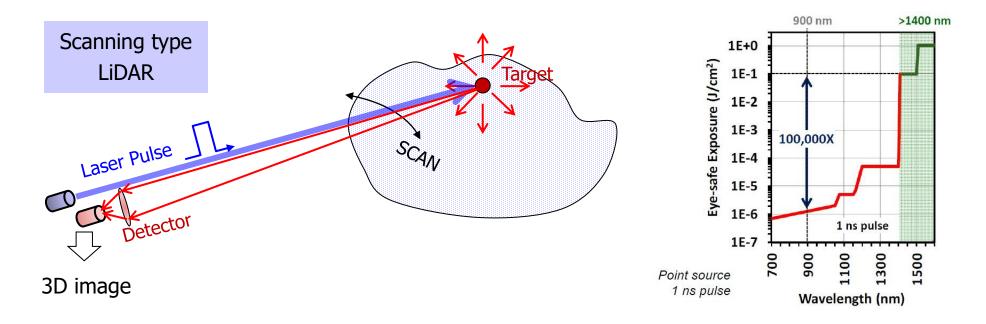
International SPAD Sensor Workshop 2022

#### $\sqrt{}$ Background

- $\sqrt{}$  InGaAs SPAD as a pixel element
- $\sqrt{}$  SPAD-based SSPM design and fabrication
- $\sqrt{}$  Test results of 64-pixel SSPM
- $\sqrt{203}$ -pixel SSPM with honeycomb arrangement of pixels
- $\checkmark$  Summary and future works



#### Background : Why InGaAs-based SPAD?



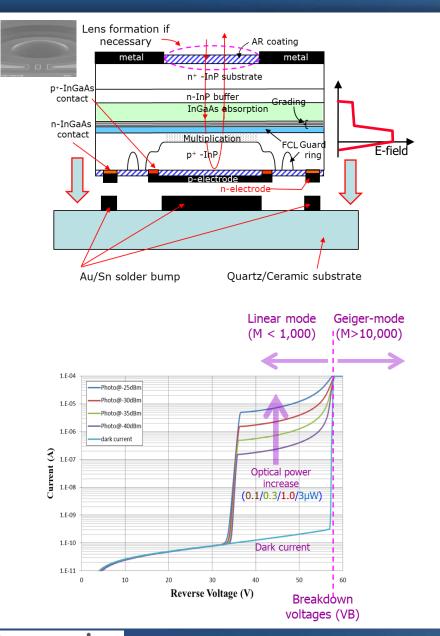
- $\sqrt{}$  The scattered laser beam from target returns to detector to measure intensity and distance by TOF
- $\sqrt{10}$  In this configuration, the laser pulse output and detector's sensitivity (detectable number of photons) determine the measurable distance.
- $\sqrt{}$  Because SPADs internally amplify tens to hundreds of thousands of times, they can detect single photon levels. Thus, long distance image available by using SPAD pixel.
- ✓ Another point to point out is that InGaAs(P)-SPAD is the best alternative to long-range LiDAR at wavelengths above 1400 nm. The reason is that it still meets the eye-safe condition even at the high power of that wavelength.



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#### InGaAs SPAD(Single Photon Avalanche Diode)



WOOLI

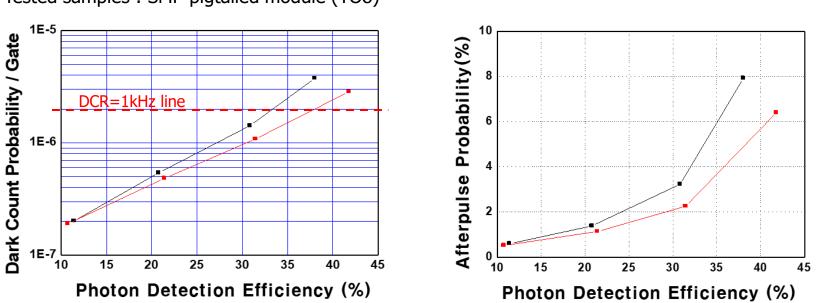
#### Features of WOORIRO SPAD

- ✓ Hi-Lo based FGR structure was used to eliminate possibility of tunneling at the maximum field region.
- $\checkmark$  Floating Guard Ring was adopted to reduce DCR noise caused by edge breakdown.
- $\sqrt{}$  For high QE, backside illumination structure was used
- $\checkmark~$  And InP-backside lens was formed directly (SSPM : to increase FF)
- $\sqrt{-}$  Very low dark current @RT & 98% of VB
- $\sqrt{}$  SPDE(Single Photon Detection Efficiency) > 30% @below 1kHz DCR
- $\sqrt{}$  DCR (Dark Count Rate) < 1kHz @ 30% SPDE
- √ For high-speed application of SPAD, DA-SPAD has been proposed and realized at 1GHz gate frequency.
  [C.W. Park et al., Optics express, vol.27, 18201(2019)]

### InGaAs SPAD performance

#### **TECT CONDITION**

- $\checkmark\,$  Gate repetition rate : 10MHz / 2ns / 6.6V
- $\sqrt{}$  Optical Input : 150ps, 0.1photon/pulse, 100kHz
- $\sqrt{}$  Chip temperature : -40°C
- $\sqrt{}$  Conventional gating technique
- $\sqrt{}$  Tested samples : SMF-pigtailed module (TO8)



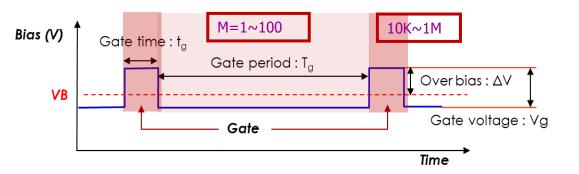
- $\sqrt{-}$  Very Low DCP or DCR noise at high detection efficiency.
- $\checkmark~$  Based on SPAD structure of good performance, InGaAs-SSPM chip has been designed and fabricated.

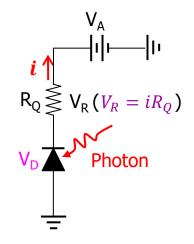


1) Active quenching (Gated mode) : Used for QKD

- ✓ Gain control is made periodically. [10,000 ~ 1,000,000 ↔ 1 ~ 100]
- $\checkmark~$  SPAD only is used without resistor.
- √ This quenching method is used for QKD (Single photon incidents on SPAD periodically)
- 2) Passive quenching (Negative Feedback : NFAD)
- $\sqrt{A}$  A series resistor(R<sub>Q</sub>) is used for negative feedback.
- $\sqrt{1}$  A large current (*i*) is generated by multiplication of millions of times
  - $\rightarrow$  bias drop by V<sub>R</sub> ( $V_R = iR_Q$ ).
  - $\rightarrow$  bias  $V_D$  in junction would be reduced from  $V_A$  to  $V_A iR_Q$ .
- $\checkmark$   $\,$  This bias drop is recovered when current is reduced  $\Rightarrow$  Ready-state
- $\sqrt{}$  This method is suitable to use for non-periodic photon incidence such as photon counting or laser range-finding(LRF).

Long-range LRF, Sensor, etc.





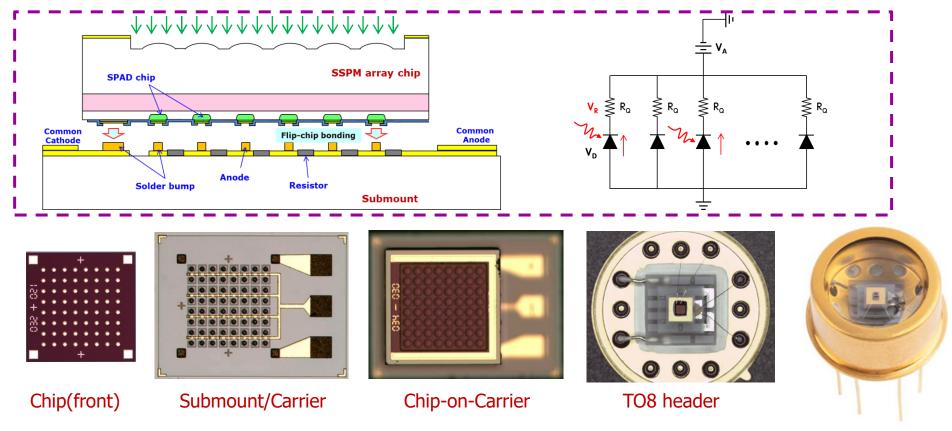


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#### SPAD-based SSPM design consideration

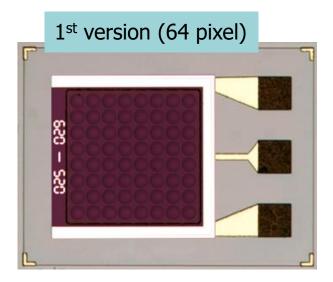
- $\sqrt{}$  SSPM(Solid-State Photo-Multiplier) : is composed of multi NFAD pixels.
- $\sqrt{}$  Backside lens was formed on substrate to increase FF(Fill Factor).
- $\checkmark$   $\,$  Each pixel has a corresponding quenching resistor.
- $\checkmark$  The current from each pixel is summed.
- $\sqrt{}$  Some pixels experience an avalanche event, but adjacent pixels that do not have an avalanche event stay on standby. These pixels act quickly when a photon is incident on that pixel.



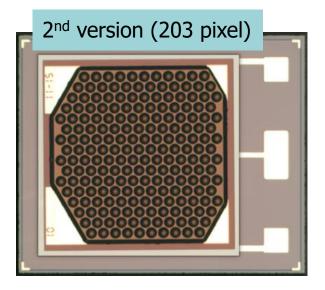


#### SPAD-based SSPM design consideration

- $\sqrt{WSSPM(W: Wooriro)}$  uses InGaAs as its absorption layer and InP as multiplication layer.
- $\sqrt{}$  WSSPM uses hundreds of SPAD and the corresponding resistor chips as micro-pixel elements.
- $\sqrt{}$  WSSPM employs isolation etching to reduce crosstalk among pixel elements.
- $\sqrt{}$  WSSPM increase FF(Fill Factor) by forming the backside InP-lens directly on the back InP substrate.
- $\sqrt{}$  Since the active size can be reduced due to the BS-lens, the performance such as PDE and Afterpulse of the pixel SPAD can be improved.



- Pixel pitch : 51 µm
- Lens diameter : 48 µm
- FF  $\cong$  69% (100% light collection in the lens)

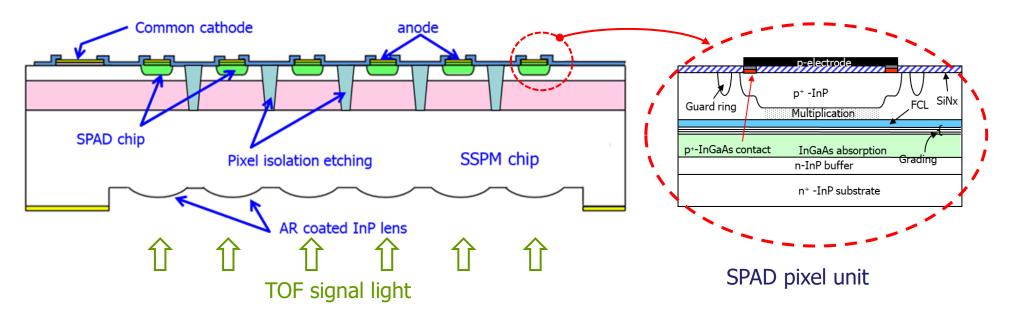


- Honeycomb structure [Regular Hexagon unit cell]
- Lens diameter : 48 µm
- FF  $\cong$  80% (100% light collection in the lens)

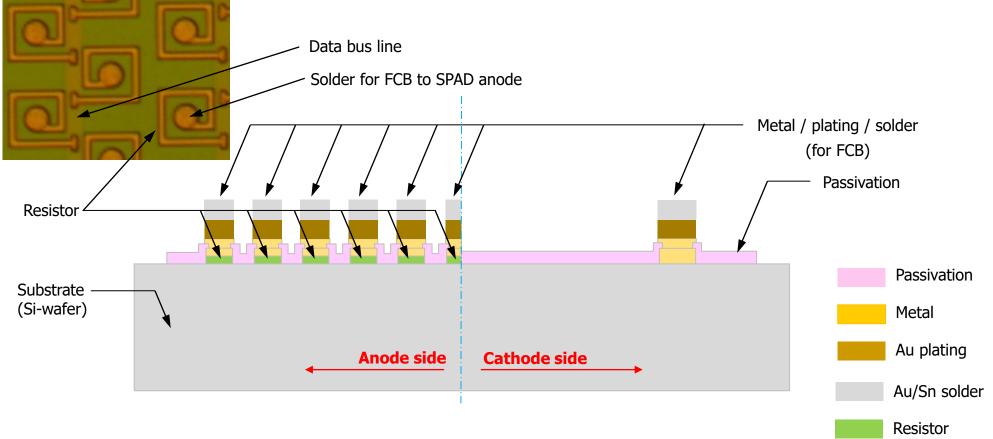


#### SPAD-based SSPM design consideration

- $\sqrt{}$  All the pixel chips have their own anode metal and mirror metal, respectively.
- $\sqrt{}$  Except for the anode and cathode contact metals, all areas on the front side of the chip are protected with SiNx.
- $\checkmark$  Every SPAD chip has its own FGR.
- $\checkmark$  All SPAD chips have absorption regions separated from each other by separation channels formed by wet chemical treatment after dry etching.
- $\sqrt{}$  Isolation-etched surface is passivated with SiNx thin film and the etched area is filled with polyimide.





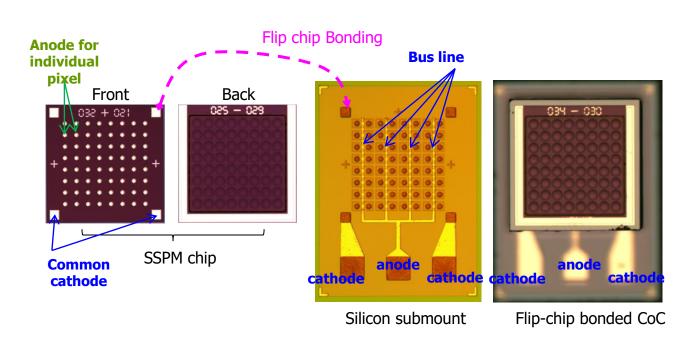


- $\sqrt{}$  The resistor is made of polysilicon and is formed on p-Si with high resistance.
- $\sqrt{}$  The resistivity is controlled by boron implantation.
- $\sqrt{}$  There exists SiO2 between Si-Substrate and polysilicon resistor.
- $\sqrt{}$  The magnitude of resistor can be changed by changing the width or length of the line. 2M $\Omega$  was best in our case.

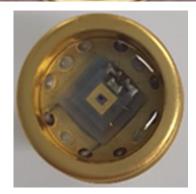


#### SSPM CoC and Module fabrication (64-pixel)

- $\sqrt{}$  The role of bus line is to sum the signals and to supply common bias(or GND) to anodes of each pixel.
- $\sqrt{}$  Flip-chip bonding of SSPM chip and submount is carried out.
- $\sqrt{}$  The CoC is mounted on TO8 header with 3-stage TEC and thermistor.
- $\sqrt{}$  Window cap sealing by resistance welding for hermetic and chip protection.



12-pin TO8 stem (6-leads are available)



**SSPM** Chip

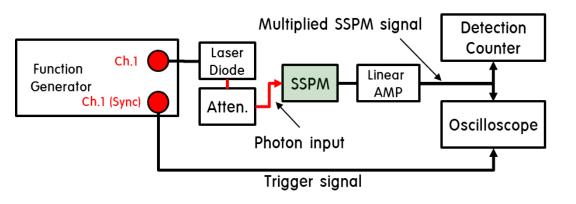


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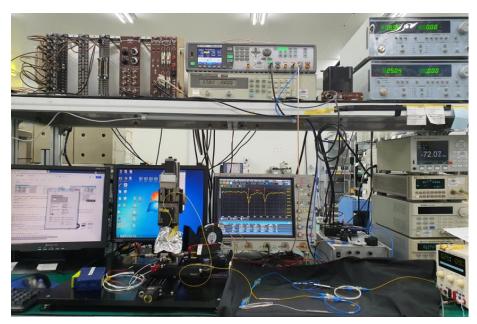


#### 64-pixel SSPM Test

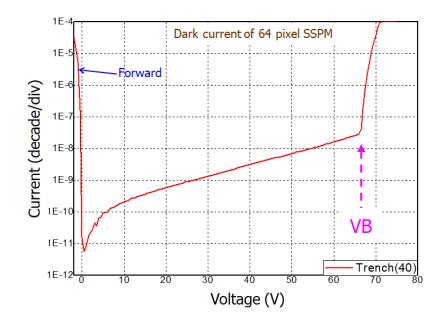
#### Block diagram of test set-up



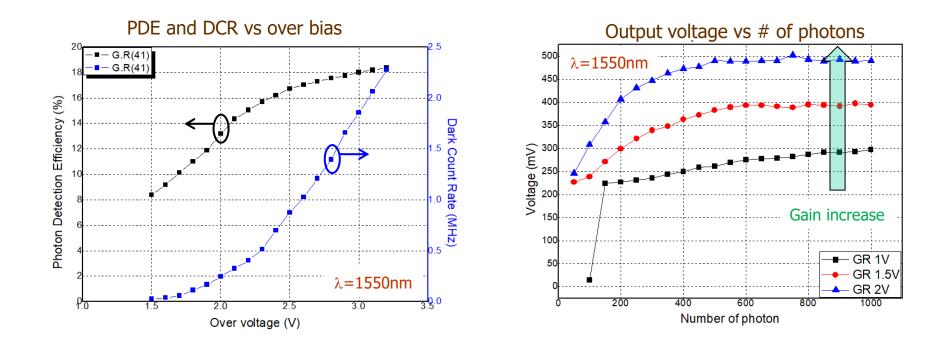
#### Test equipment



- $\sqrt{}$  Photon incidence through 62.5µm MMF without any beam steering.
- √ Overbias(V<sub>apply</sub> VB) was controlled 2.0 or 2.5V for the performance optimization.
- $\checkmark$  Breakdown voltage was defined by the curvature of dark current.
- $\sqrt{}$  Averaged dark current of unit pixel : ~ 20nA/64pixels ≅ 300pA at RT





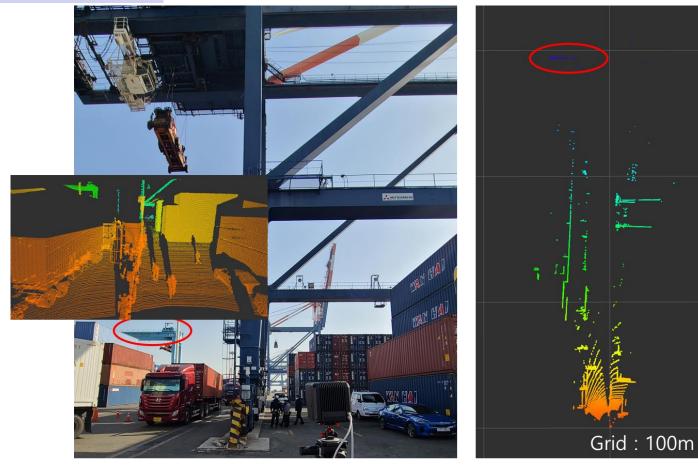


- $\checkmark~$  DCR is not bad even at 18% of PDE.
- $\sqrt{}$  The photon number resolving range is small  $\Rightarrow$  because # of pixel is small
- ✓ New design ⇒ Increase # of pixels / Increases the distance between active region and trench mesa surface / Decrease active size / Increase FF (honeycomb arrangement of pixel)



### Point cloud 3D image (64-pixel SSPM)

#### (Outdoor Application)



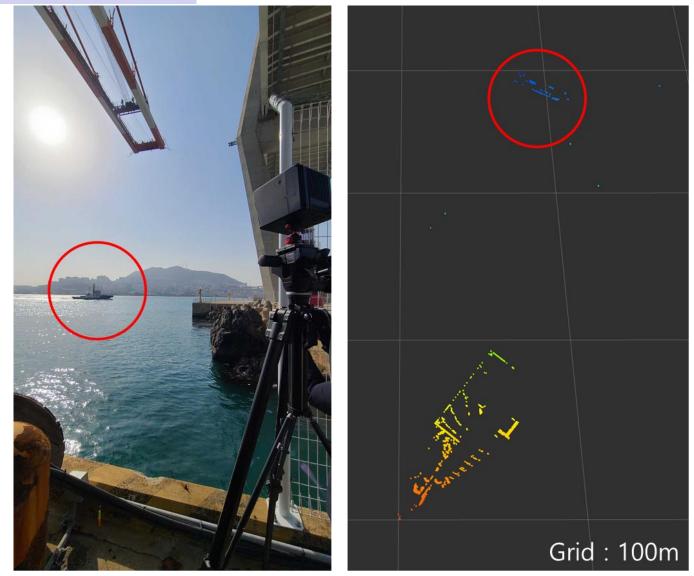


- $\checkmark\,$  Point cloud 3D images were generated by SOS Lab (LiDAR-related start-up company) using 64-pixel SSPM.
- $\sqrt{}$  A 200-pixels WSSPM will show better performance, but 3D point cloud tests were not done yet.



#### Point cloud 3D image (64 pixel SSPM)

#### (Outdoor Application)



Point cloud 3D images were generated by SOS Lab using 64-pixel SSPM

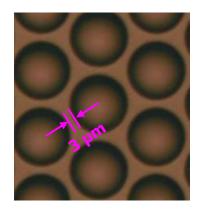


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- $\sqrt{}$  64 pixels  $\Rightarrow$  203 pixels of NFAD.
- $\checkmark$  Honeycomb arrangement of pixels.
- $\sqrt{}$  FF of the new SSPM is increased from 69% to 80% by lens arrangement in honeycomb structure



Backside lens image

Chip front image

Isolation etch (InP & InGaAs)

Metal for Cathode & reflection FGR is formed here

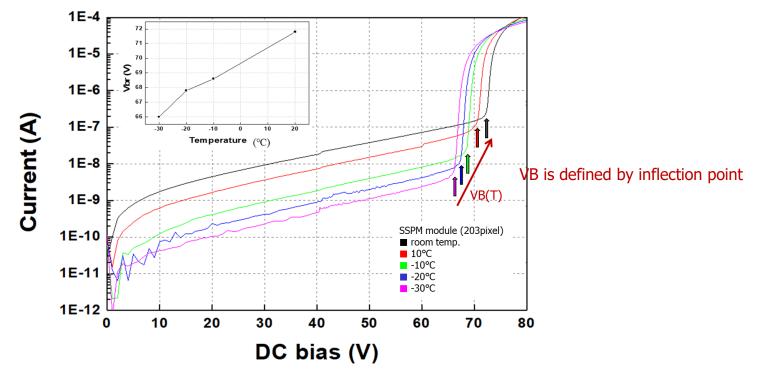
FIG. Honeycomb arrangement of SSPM Pixels

Chip front image



#### SPAD-based 203 pixel : Dark current

- $\sqrt{}$  At voltages above VB, the total resistance is ~  $2M\Omega/200 \approx 10k\Omega$  if individual resistors have  $2M\Omega$ .
- $\sqrt{}$  Temp. coefficient was measured ~ 117 mV/°C



Vbr [V]				Dark current [A] @0.9Vbr				Temp. coeff.
RT	-10°C	-20°C	-30°C	RT	-10°C	-20°C	-30°C	[V/°C]
71.8	68.6	67.8	66	9.77E-8	9.33E-9	4.48E-9	2.24E-9	0.117
				480 pA	46 pA	22 pA	11 pA	

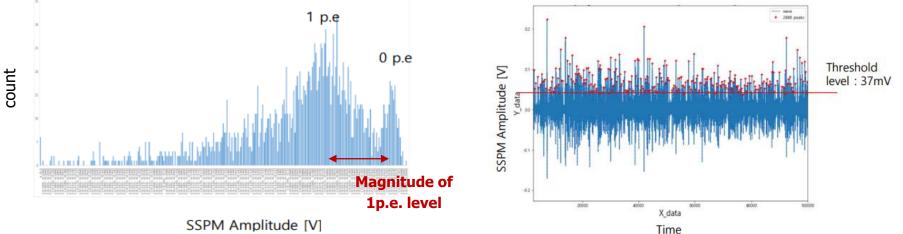
 $\Rightarrow$  I<sub>D</sub>(203-pixel)

 $\Rightarrow$  I<sub>D</sub>(single pixel-Average)



#### SPAD-based 203 pixel : PDE and DCR

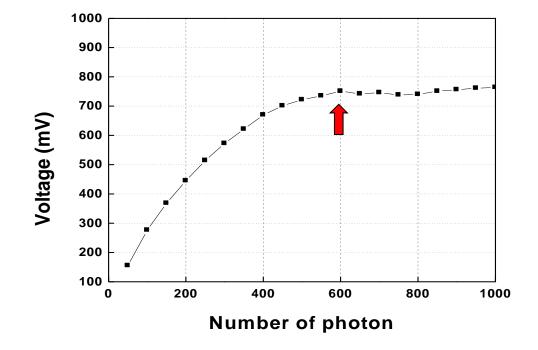
- $\sqrt{}$  To measure PDE and DCR, the magnitude of the output level(1-p.e.) for single photon is measured. For ex., sample #6 has 74 mV of 1-p.e. level.
- $\sqrt{}$  Threshold voltage for discrimination is taken as a half of 1-p.e. In this case V<sub>th</sub> =37 mV
- $\sqrt{}$  DCR is counted without photon incidence.
- $\sqrt{}$  PDE is measured and calculated under photon incidence. PDE ~ 25.6% @17.7MHz of DCR



Sample #	TEC Temp. [°C]	V <sub>bias</sub> [V]	Number of Photon	1 p.e. Level [mV]	PDE[%]	DCR*[MHz] (Threshold Level 0.5p.e)
6		68.7	7.8	64	18.7	5.5
		69.2	7.8	74	25.6	17.7
14	-20	68.67	15.9	46	10.8	9.5
		69.66	7.8	70	16.9	10
		70.26	6.98	70	23.1	11



#### Photon number resolving result of 203-pixel SSPM

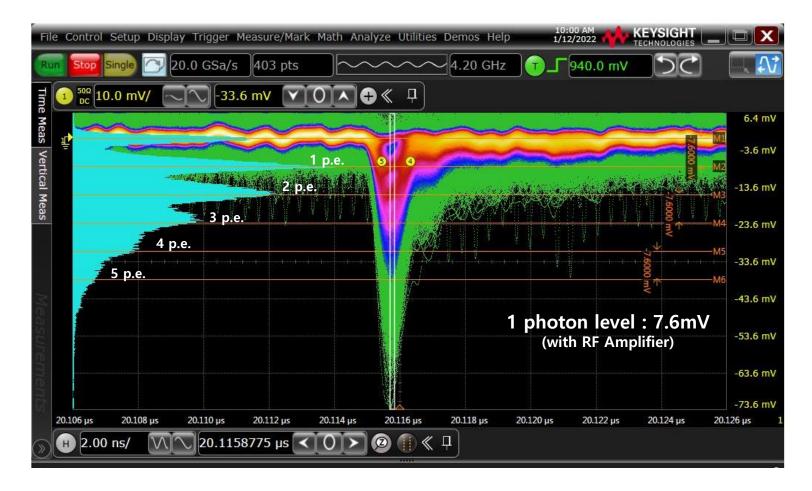


- $\checkmark$  The maximum number of photons that can be counted is 600 for a 203-pixel SSPM.
- $\sqrt{}$  We can say that as a photon number resolver, the linearity improves as the number of pixels increases.



Optical Input : 280ps / 100kHz / 5 photon Over bias : 2.5V

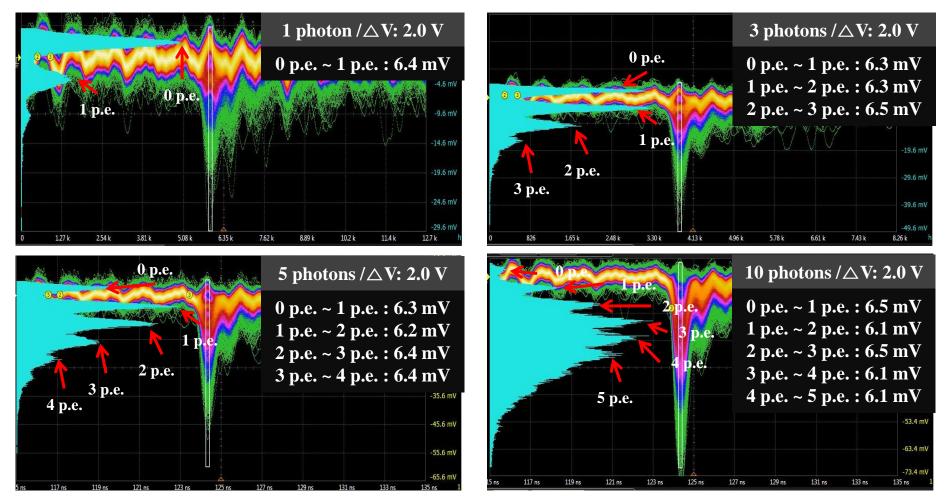
TEC surface temperature : -20°C





## Photon number resolving performance of 203 pixels SSPM

Optical Input : 280ps & 100kHz / Over bias : 2.0 V / TEC surface temperature : -20°C



- 1. SSPM can count photon number
- 2. The amplitude of SSPM output increases if # of incident photons increase.
- 3. Can obtain intensity information from analysis of cumulative statistics.



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#### Summary

- $\checkmark\,$  InGaAs SPAD-based SSPMs with excellent performance were successfully fabricated.
- $\sqrt{}$  SSPM is composed of InGaAs-SPAD chip array and resistor chip array fabricated on Si-substrate.
- $\sqrt{10}$  The 2<sup>nd</sup> ver. of SSPM(203 pixels) showed 25.6% of PDE @ 17.7 MHz DCR.
- $\sqrt{-}$  The 2<sup>nd</sup> ver. of SSPM was not applied to 3D LiDAR Rx, yet.
- $\checkmark$  A 3D point cloud image of an object 300 meters away was successfully obtained by using the 1<sup>st</sup> ver. of SSPM(64-pixel).

Further Works

- $\sqrt{}$  More compact and smaller pixel to optimize PDE and DCR.
- $\sqrt{}$  Reliability study and failure analysis.

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